Notice of References Cited Examiner

Applicant(s)/Patent Under
Reexamination
LORENZ ET AL.
Art Unit

2825

Helen Rossoshek

Application/Control No.

Page 1 of 2

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	А	US-6,178,544	01-2001	Syo	716/20
	В	US-2002/0120906	08-2002	Xia et al.	716/2
	С	US-6,317,704	11-2001	Furuhata et al.	703/2
	D	US-6,708,141	03-2004	Schaff et al.	703/2
	E	US-6,718,291	04-2004	Shapiro et al.	703/2
	F	US-2004/0117163	06-2004	Rivara	703/002
	G	US-2005/0131662	06-2005	Ascenzi et al.	703/011
	Н	US-2004/0062786	04-2004	Ascenzi et al.	424/423
	1	US-6,121,973	09-2000	Itoh et al.	345/423
	J	US-6,259,453 B1	07-2001	Itoh et al.	345/423
	К	US-			
	L	US-			
	М	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	Z					
	0					
	Р					
	Q					
	R					
	S					
	Т					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Bächtold et al., "An error indicator and automatic adaptive meshing for electrostatic boundary element simulations", Dec. 1997, Transactions on Volume 16, Issue 12, Pages: 1439 - 1446
	٧	Hung et al., "Low-order models for fast dynamical simulation of MEMS microstructures", 16-19 June 1997, Solid State Sensors and Actuators, TRANSDUCERS '97, International Conference on, Volume 2, Page(s):1101 - 1104 vol.2 □□
	w	Senturia et al., "Simulating the behavior of MEMS devices: computational methods and needs", JanMarch 1997, Science & Engineering], Volume 4, Issue 1, Page(s):30 - 43 □□
	×	Aluru et al., "A point collocation method for meshless analysis of microelectronic and microelectromechanical devices", 19-21 Oct. 1998, Computational Electronics, IWCE-6. Extended Abstracts of 1998 Sixth International Workshop on, Page(s):54 - 57

^{*}A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.

Notice of References Cited Application/Control No. 10/665,885 Examiner Helen Rossoshek Applicant(s)/Patent Under Reexamination LORENZ ET AL. Page 2 of 2

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	Α	US-			
	В	US-			
	С	US-			
	D	US-			
	Е	US-			
	F	US-			
	G	US-			
	H	US-			
	1	US-			
	J	US-			
	κ	US-			
	L	US-			
	М	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	0			•		
	Р					
	σ					
	R					
	s					
	Т					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Gilbert et al., "Implementation of MEMCAD system for electrostatic and mechanical analysis of complex structures from mask descriptions", 7-10 Feb. 1993, Micro Electro Mechanical Systems, Proceedings ' Page(s):207 - 212
	٧	Bochobza et al., An efficient relaxation based DIPIE algorithm for computer aided design of electrostatic actuators", 20-24 Jan. 2002, The Fifteenth IEEE International Conference on, Page(s):200 - 203
	×	Bochobza et al., , "An efficient DIPIE algorithm for CAD of electrostatically actuated MEMS devices", Oct. 2002, Microelectromechanical Systems, Journal of, Volume 11, Issue 5, Page(s):612 - 620
	х	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.